

Title (en)
STATION AND METHOD FOR MEASURING THE PARTICULATE CONTAMINATION OF A TRANSPORT CHAMBER FOR CONVEYING AND ATMOSPHERICALLY STORING SEMICONDUCTOR SUBSTRATES

Title (de)
STATION UND VERFAHREN ZUR MESSUNG DER PARTIKELKONTAMINATION EINER TRANSPORTKAMMER ZUM FÖRDERN UND ATMOSPHERISCHEN LAGERN VON HALBLEITERSUBSTRATEN

Title (fr)
STATION ET PROCEDE DE MESURE DE LA CONTAMINATION EN PARTICULES D'UNE ENCEINTE DE TRANSPORT POUR LE CONVOYAGE ET LE STOCKAGE ATMOSPHERIQUE DE SUBSTRATS SEMI-CONDUCTEURS

Publication
EP 2926369 B1 20170222 (FR)

Application
EP 13811809 A 20131129

Priority
• FR 1261453 A 20121130
• EP 2013075076 W 20131129

Abstract (en)
[origin: WO2014083152A1] The present invention relates to a method for measuring the particulate contamination of a transport chamber for conveying and atmospherically storing semiconductor substrates, used in a measuring station. The measurement method comprises: a step in which the measurement module (5) is coupled to a rigid enclosure (2), defining a first measurement space (V1) between the measurement interface enclosure (16) and the rigid enclosure (2) coupled such as to carry out a measurement of the contamination of the inner walls of the rigid enclosure (2), and a step in which the door (3) is coupled to the measurement module (5), defining a second measurement space (V2) between said measurement surface (22) and the facing door (3), in order to carry out a measurement of the contamination of the door (3). The invention further relates to an associated measurement station.

IPC 8 full level
H01L 21/673 (2006.01); **G01N 33/00** (2006.01)

CPC (source: CN EP US)
G01N 33/0009 (2013.01 - CN EP US); **H01L 21/673** (2013.01 - US); **H01L 21/67389** (2013.01 - CN EP US)

Designated contracting state (EPC)
AL AT BE BG CH CY CZ DE DK EE ES FI FR GB GR HR HU IE IS IT LI LT LU LV MC MK MT NL NO PL PT RO RS SE SI SK SM TR

DOCDB simple family (publication)
WO 2014083152 A1 20140605; CN 104823271 A 20150805; CN 104823271 B 20170609; EP 2926369 A1 20151007; EP 2926369 B1 20170222; FR 2999016 A1 20140606; JP 2016506065 A 20160225; JP 6321671 B2 20180509; KR 102179362 B1 20201116; KR 20150091145 A 20150807; TW 201432834 A 20140816; TW I646612 B 20190101; US 2015301007 A1 20151022; US 9816974 B2 20171114

DOCDB simple family (application)
EP 2013075076 W 20131129; CN 201380062199 A 20131129; EP 13811809 A 20131129; FR 1261453 A 20121130; JP 2015544477 A 20131129; KR 20157017431 A 20131129; TW 102143559 A 20131128; US 201314443745 A 20131129